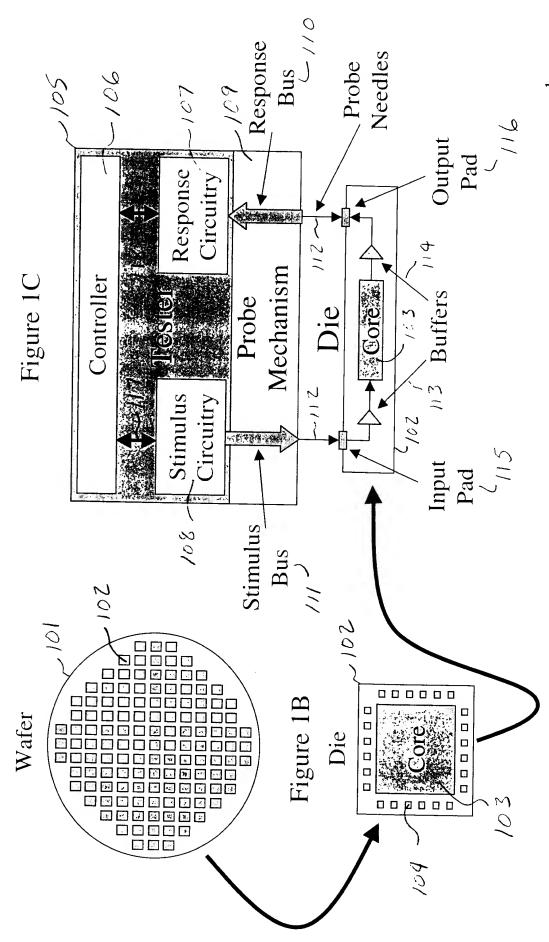
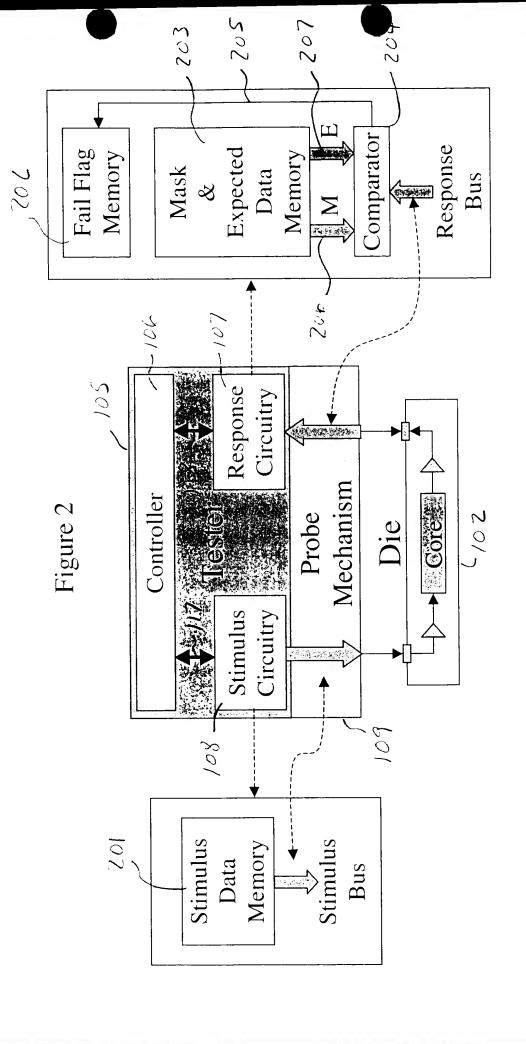
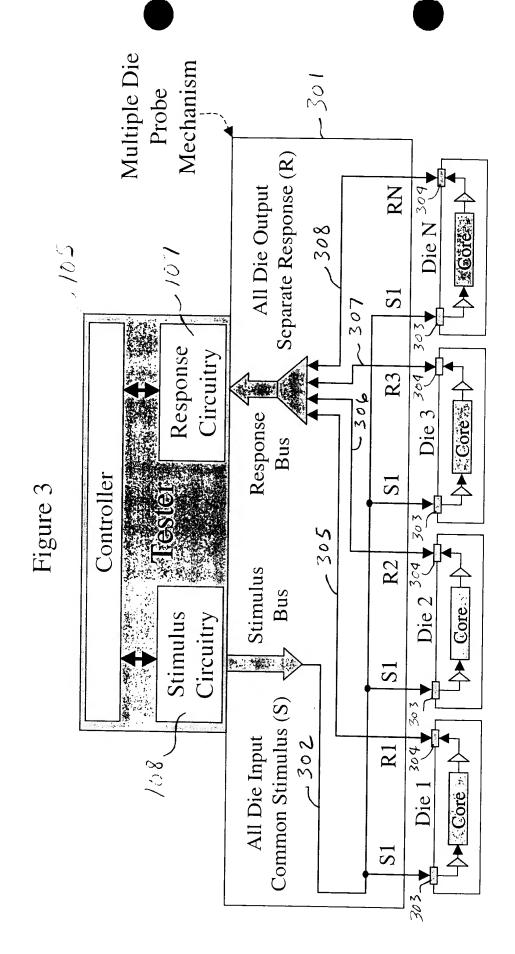
Conventional Wafer Test Example

Figure 1A

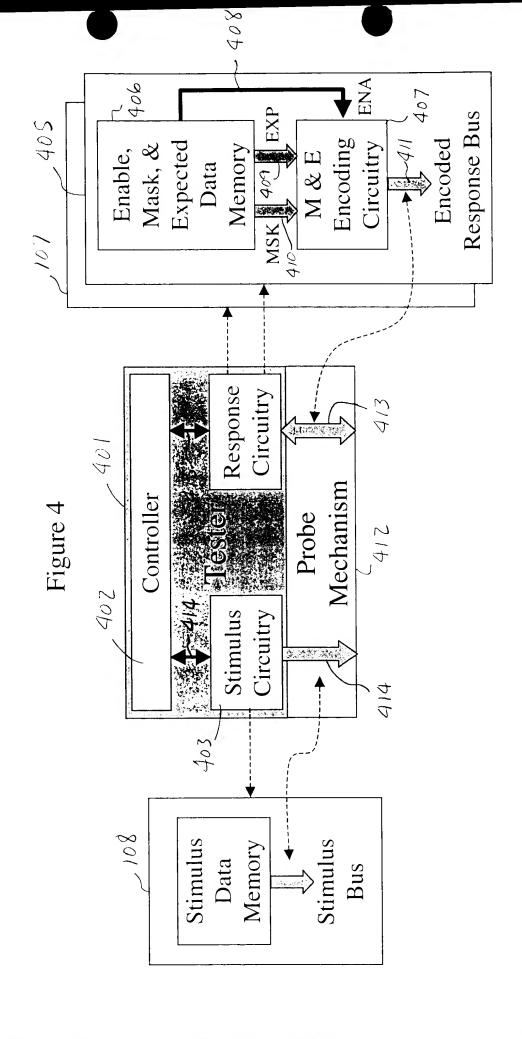






(Sum of R1-RN) <= (Tester Response Bus Width)

Adapting Testers To Support Improved Wafer Testing



Mask & Expected Encoding Circuitry

Figure 5A

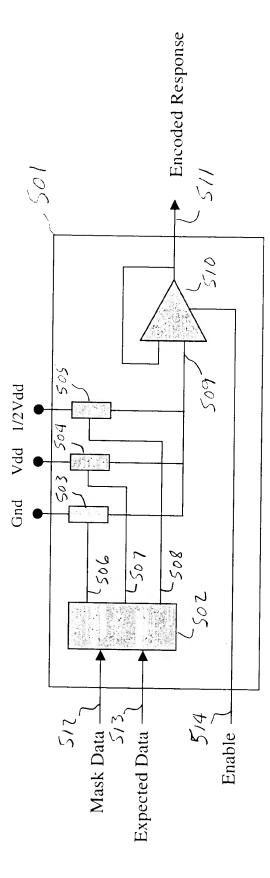
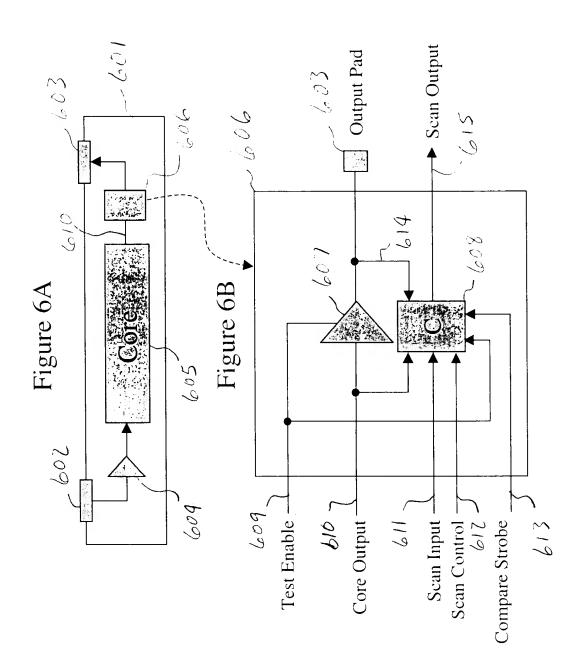


Figure 5B

| _           |          |                |                |          |
|-------------|----------|----------------|----------------|----------|
| Output Mode | Disabled | Low            | High           | Mask     |
| ENR         | Z        | Gnd            | Vdd            | 1/2Vdd   |
| EXP         | 0        | 0              | $\vdash$       | ×        |
| MSK         | 0        | 0              | 0              | $\vdash$ |
| ENA         | 0        | $\leftarrow$ I | $\leftarrow$ i | Π        |



Maskable Comparator For 2-State Outputs

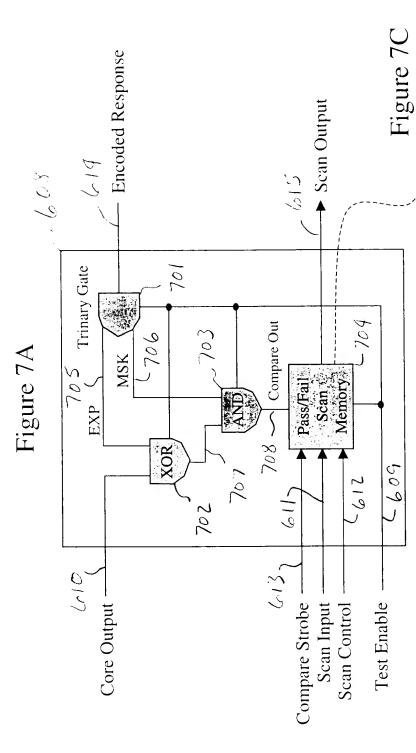


Figure 7B

| TEN      | ENR    | MSK      | MSK EXP  | Function Performed |
|----------|--------|----------|----------|--------------------|
| 0        | ×      | ×        | X        | Test Disabled      |
| $\vdash$ | Gnd    | <b>H</b> | 0        | Compare Low        |
| $\vdash$ | Vdd    | H        | $\vdash$ | Compare High       |
| $\vdash$ | 1/2Vdd | 0        | ×        | Mask Compare       |

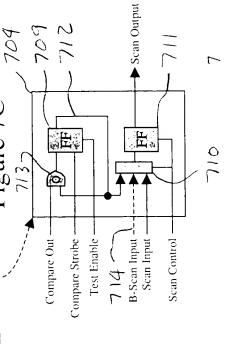


Figure 8A

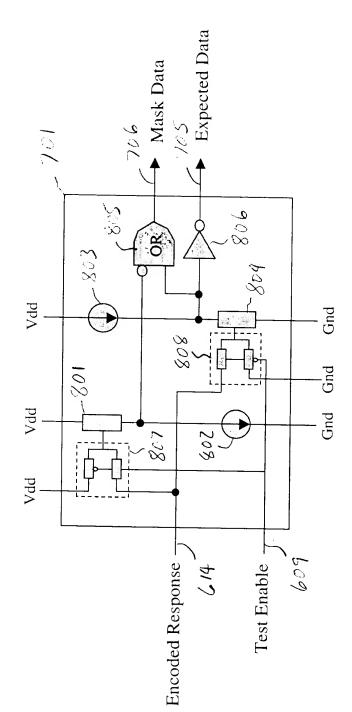
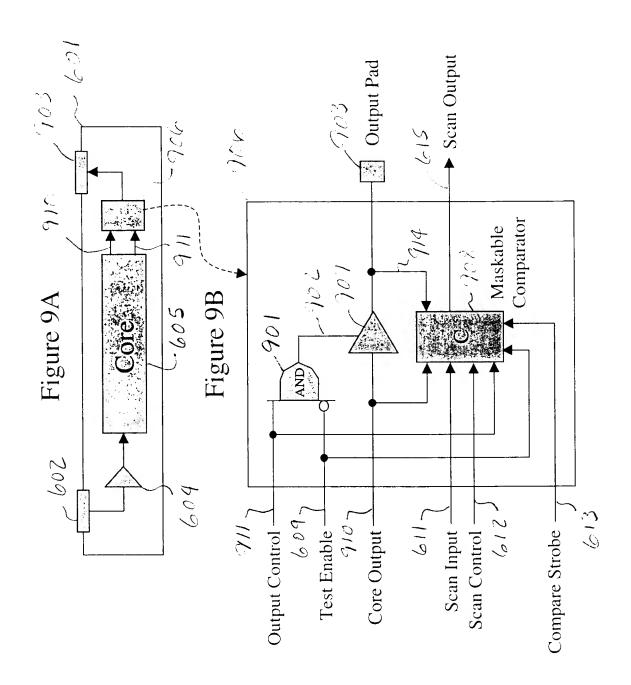


Figure 8B

| TEN          | ENR    | MSK          | EXP      | Function Performed |
|--------------|--------|--------------|----------|--------------------|
| 0            | ×      | Н            | 0        | Gate Disabled      |
| $\leftarrow$ | Gnd    | $\leftarrow$ | 0        | Output a Low       |
| $\vdash$     | Vdd    | $\vdash$     | $\vdash$ | Output a High      |
| ⊣            | 1/2Vdd | 0            | ×        | ಹ                  |

Adapting Die 3-State Outputs To Support Improved Wafer Testing



Maskable Comparator For 3-State Outputs

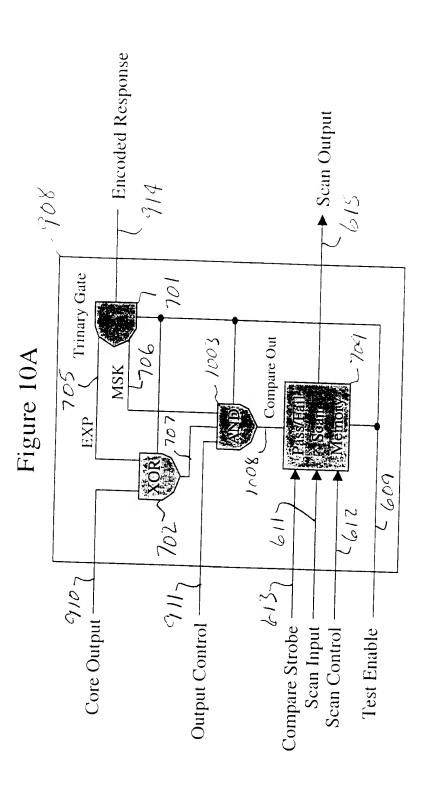
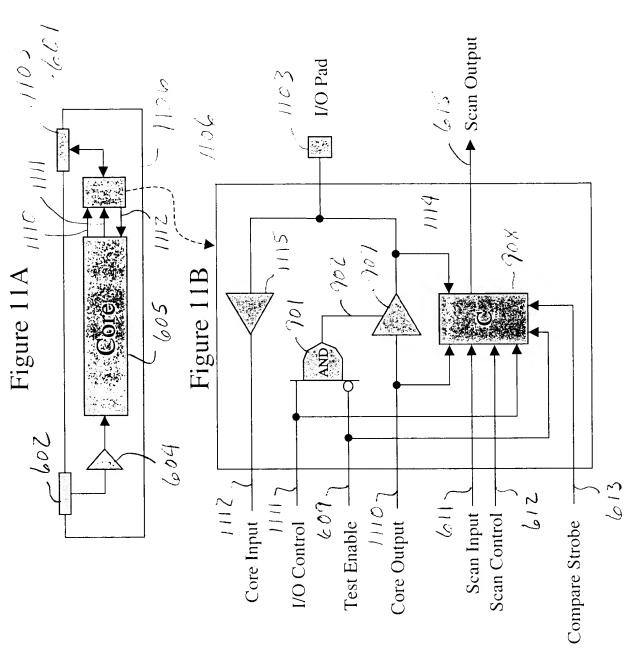


Figure 10**8** 

| _             |                     | _             |                  |             | _          |              |         |              |                                       |                     |                        |
|---------------|---------------------|---------------|------------------|-------------|------------|--------------|---------|--------------|---------------------------------------|---------------------|------------------------|
| Fluction Dove | Tailclion Feriormed | Test Disabled | TO THE THE TOTAL | Compare Low | MOT ) 15 4 | Compare High |         | Mask Compare |                                       | Test Output Confrol | - HOHOTTON () 11 4 - 1 |
| MSK FXP       | 1111                | ×             | ,                | 0 7         | ,          |              | ;       | ×            | , ,                                   | 1 1/0 1             |                        |
| ENR           |                     | ×             | 2 %              | 2115        | C C 11     | 700          | 1/21123 | 1/2/dd       | C C C C C C C C C C C C C C C C C C C | שוומ/ עממ           |                        |
| TEN           |                     | )             | _                | 4           | _          | 7            | _       | 4            | 1                                     | 4                   |                        |
| 0C            | 1 1                 | ≺'            | ·                | ł           |            | 1            |         | +            | 0                                     | )                   |                        |

Adapting Die Input/Outputs To Support Improved Wafer Testing



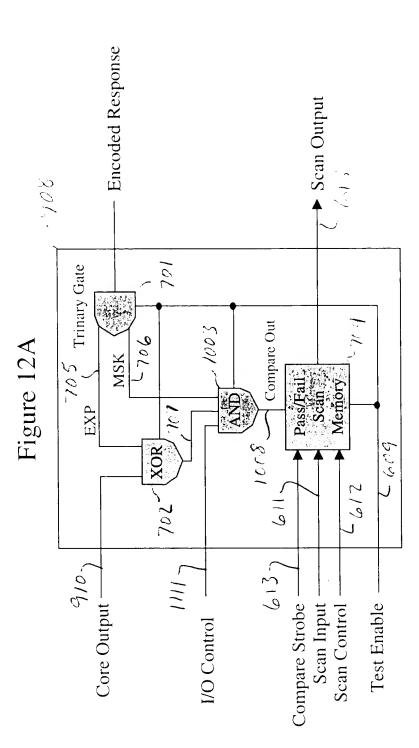
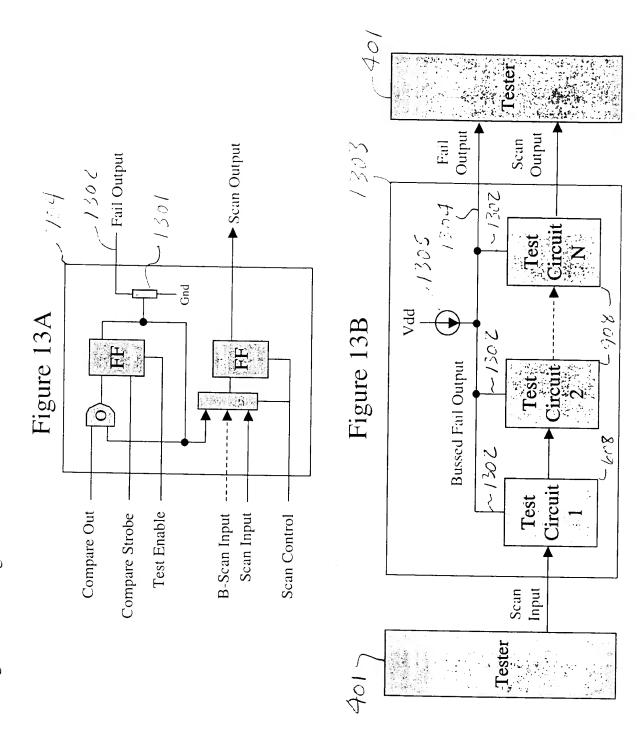
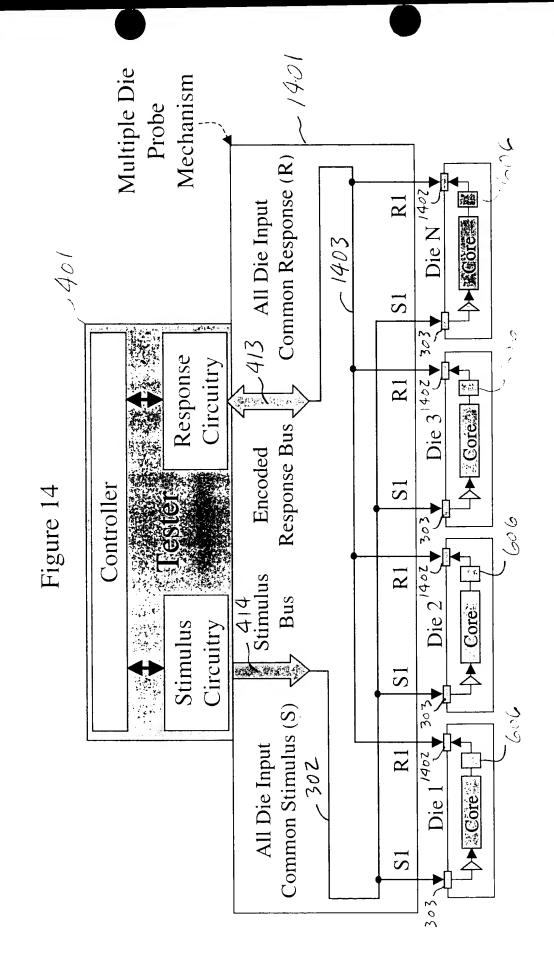


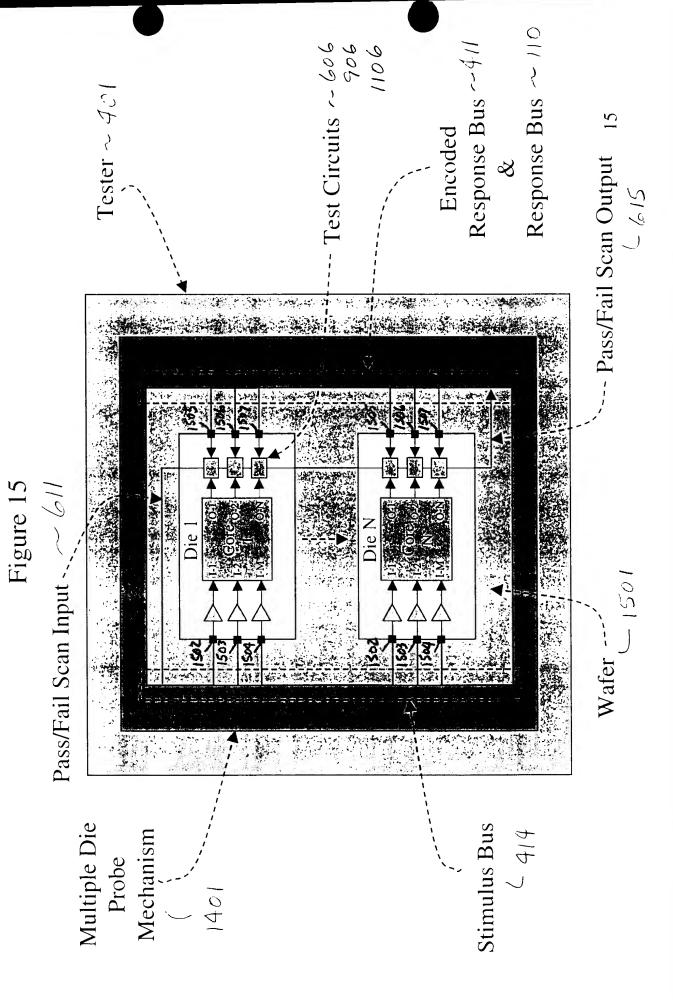
Figure 12B

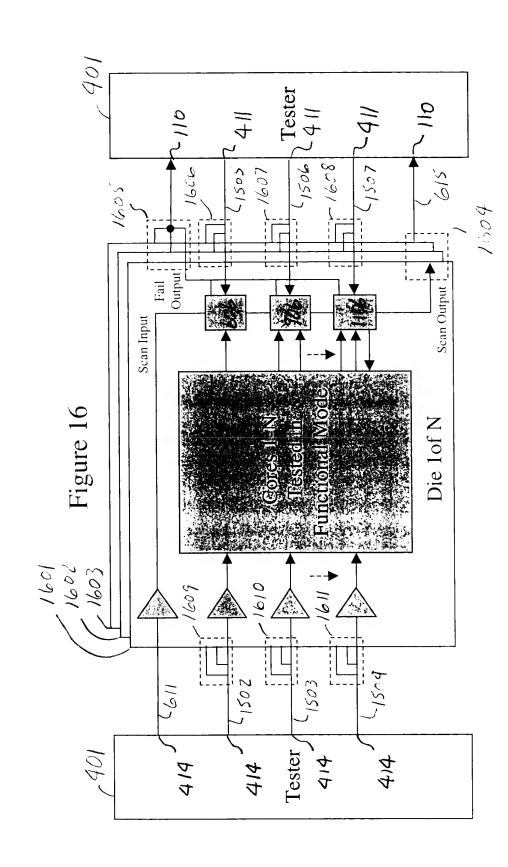
|                    |               |              |              |              |                  |                | _ |
|--------------------|---------------|--------------|--------------|--------------|------------------|----------------|---|
| Function Performed | Test Disabled | Compare Low  | Compare High | Mask Compare | Test I/O Control | Input Stimulus |   |
| MSK EXP            | ×             | 0            | $\dashv$     | ×            | 0/1              | 0/1            |   |
| MSK                | ×             | $\vdash$     | ₩            | 0            | <del>,  </del>   | $\vdash$       |   |
| ENR                | ×             | Gnd          | Vdd          | 1/2Vdd       | Gnd/Vdd          | Gnd/Vdd        |   |
| TEN                | 0             | $\vdash$     | $\vdash$     | $\leftarrow$ | $\vdash$         | $\vdash$       |   |
| TOC                | ×             | $\leftarrow$ | $\leftarrow$ | $\vdash$     | 0                | 0              |   |

Fail Output for Diagnostic Testing

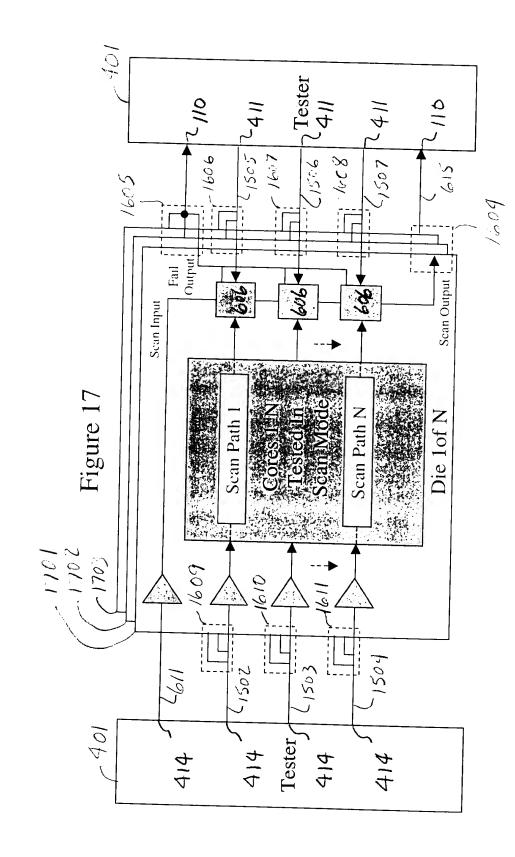




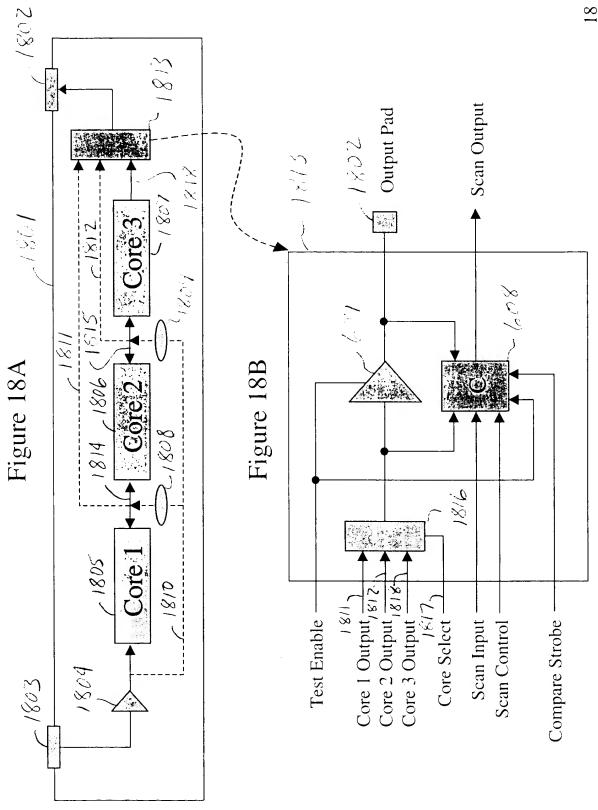




Die Being Tested in Scan Mode



Multiple Embedded IP Core Sub-Circuits Testing System-On-Chip Die having



Adapting Wafers To Support Improved Wafer Testing

Pad Contacting Grid Lines Wafer Processed with 1910 RI √sı Die N Probe Contact R1 Grid Line 101 1909 R1 Response Circuitry Die 3 -Grid Lines-Response Bus Encoded S1 > Needles Figure 19 Controller RI \$1908 Stimulus 1909 Bus Core Die 2 Stimulus Circuitry SI S1 Probe Contact S1 Grid Line 9061-0 1907 RI Pad Contacts ▼ Core :-

Multiple Wafer Mechanism Probe 1401 Common Response (R) All Wafers Input Die N Wafer N 1902 R1 Die 1 Die 2 1901 S Response Circuitry Die N Wafer 3 1902 Encoded Response Bus R1 Grid Lines Die 1 Die 2 Wafers Processed with Figure 19A 1903 Controller S1 Die 2 💢 Die N Wafer 2 1902 Stimulus RI Bus Circuitry Stimulus Die 1 S1 Common Stimulus (S) All Wafers Input Die N R1 Wafer 1 1902 Die 2 1901 Die 1 SI

Pad Contacting Grid Lines

